DEC 27 1005 E

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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 8916

Hiroshi SOTOZAKI et al.

Attorney Docket No. 2004_0208

Serial No. 10/774,489

Group Art Unit 1763

Filed February 10, 2004

Examiner Sylvia MacArthur

METHOD AND APPARATUS FOR POLISHING A SUBSTRATE

Mail Stop: AF

extered per MCC

AMENDMENT

THE COMMISSIONER IS AUTHORIZED TO CHARGE ARY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action mailed September 26, 2005, please amend the above-identified application as follows: